



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Vyvoda et al.

Application No.: 09/776009

Filed: 02/02/2001

Title: Wafer Surface that Facilitates Particle
Removal

Attorney Docket No.: MA-027

Group Art Unit: 2814

Examiner: Anh D. Mai

Assistant Commissioner for Patents
PO Box 1450
Alexandria VA 22313-1450

REQUEST FOR CONTINUE EXAMINATION

Applicants request continued examination under 37 CFR 1.114. The claim amendments and remarks included herein constitute the required submission.

CLAIM AMENDMENTS

Please amend claims 1, 30, and 44 as in the following list of current claims.
Please cancel claims 6, 35, and 49. Please add new claims 57-62.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Mail Stop RCE, PO Box 1450, Alexandria VA 22313-1450 on the date shown below.

7/23/03
Date


Pamela J. Squyres